

Short Program MNE 2016

	Monday	Tuesday	Wednesday	Thursday	Friday	
Lecture Hall	Strauß	Stolz	Schubert	Strauß	Stolz	Schubert
08:00				Keynote Takehiko Iwanaga		
08:15						
08:30				Keynote Michiel Vellekoop		
08:45	Opening		Keynote Nico de Rooij			
09:00		Keynote David Egglestone	MNE Fellow Award + MEE YIA	Poster Award + u-n-Graph Contest Winners	C7.2	
09:15			Keynote Veena Misra		A5 invited	
09:30		Keynote Franz Kreupl		Break/Coffee/Exhibition	A5	
09:45			Break/Coffee/Exhibition		B4	
10:00		Break/Coffee/Exhibition		Break/Coffee/Exhibition	B4 invited	
10:15			YIA invited	C7 invited		
10:30			A7	A9		
10:45			D4	C2		
11:00	C11-1 invited	D6			Keynote Peter Ertl	
11:15		D6 invited		C7.1	Closing Remarks	
11:30		B1				
11:45	C11.1		A7 invited			
12:00		D6		C2 invited		
12:15		B1 invited				
12:30						
12:45		Lunch	Lunch	Lunch	no exhibition on Friday	
13:00						
13:15						
13:30						
13:45	C1 invited	A4.1	A3 invited	C11-3 invited	B3	
14:00		B7	D5	A4.2	B3 invited	
14:15						
14:30	C1.1		A3	C11.3	B3	
14:45		B7 invited	D5 invited	A4 invited		
15:00						
15:15		Break/Coffee/Exhibition	Break/Coffee/Exhibition	Break/Coffee/Exhibition		
15:30						
15:45		D2 invited				
16:00	C6		C11.2.	A1	D1.1	
16:15		D2				
16:30		B2		C1.3	A6	
16:45				D1.2		
17:00		Poster Session / Exhibition	Poster Session / Exhibition	Poster Session / Exhibition	Special Session SNM	
17:15						
17:30						
17:45						
18:00	Registration & Welcome Reception					
18:15			bus transfer			
18:30						
18:45						
19:00			Conference Dinner @ Viennese Heurigen			
				Young People Party Meeting (Praterdome)		

A. Micro- and Nanopatterning

- A1 Photon lithography
- A3 Electron and ion beam lithography
- A4.1 Soft lithography 1
- A4.2 Soft lithography 2
- A5 Materials for micro- and nanolithography
- A6 Directed Self Assembly
- A7 Tip based patterning
- A9 Novel techniques

C. Micro/Nano Devices and Systems

- C1.1 MEMS / NEMS 1 - actuation
- C1.2 MEMS / NEMS 2 - processing
- C1.3 MEMS / NEMS 3 - energy harvest
- C2 Micro and nano fluidic systems
- C6 Device and system modelling
- C7.1 Micro / Nano devices for physical science 1
- C7.2 Micro / Nano devices for physical science 2 - optical devices
- C11.1 Applications 1 - sensors
- C11.2 Applications 2 - memory
- C11.3 Applications 3 - fabrication

B. Micro- and Nanofabrication

- B1 Pattern transfer
- B2 Plasma etching
- B3 Beam induced deposition and 3D microprinting
- B4 3D nanomanufacturing
- B7 (Nano-) Metrology

D. MNE for Life Sciences and Biology

- D1.1 Sensing 1 - biomolecules
- D1.2 Sensing 2
- D2 Lab-on-a-Chip
- D4 Micro / Nanofluidics for bio / life sciences
- D5 System design and fabrication
- D6 Applications